- 20. An apparatus for loading substrates upon and unloading substrates from at least two processing stations, wherein said apparatus is provided with a conveying device for a linear transport of substrates, and at least one rotatable handling device for transporting substrates between said conveying device and said processing stations, wherein said conveying device is disposed between said at least two processing stations, and wherein said at least one handling device is disposed above said conveying device.
- 21. An apparatus according to claim 20, wherein a point of rotation of said at least one handling device is disposed upon a central axis of said conveying device.
- 22. An apparatus according to claim 20, wherein said at least one handling device is provided with receivers for substrates, and wherein said receivers are disposed upon a circumferential circle.
- 23. An apparatus according to claim 22, wherein said receivers are uniformly spaced apart upon said circumferential circle.
- 24. An apparatus according to claim 22, wherein said at least one handling device is provided with radial arms, and wherein said receivers are disposed on said arms.
- 25. An apparatus according to claim 20, wherein said conveying device is provided with a conveyor belt.
- 26. An apparatus according to claim 25, wherein said conveyor belt extends between a loading station and an unloading station.

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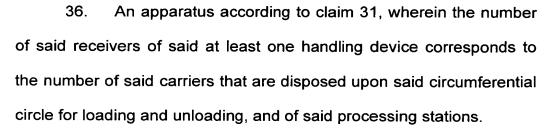
- 27. An apparatus according to claim 25, wherein said conveyor belt is provided with carriers for substrates.
- 28. An apparatus according to claim 27, wherein said carriers are uniformly spaced apart in a direction of movement of said conveyor belt.
- 29. An apparatus according to claim 27, wherein said carriers are disposed on a central axis of said conveyor belt.
- 30. An apparatus according to claim 27, wherein respectively at least two of said carriers are symmetrically disposed relative to a central axis of said conveyor belt.
- 31. An apparatus according to claim 27, wherein for a loading and unloading of substrates, at least two of said carriers are adapted to be disposed upon said circumferential circle.
- 32. An apparatus according to claim 22, wherein central receiving points of said processing stations are disposed upon said circumferential circle.
- 33. An apparatus according to claim 32, wherein said processing stations are disposed in pairs diametrically across from one another upon said circumferential circle.
- 34. An apparatus according to claim 33, wherein the processing stations within said pairs are of the same type.
- 35. An apparatus according to claim 22, wherein a common drive means is provided for driving those processing stations that are disposed adjacent one another upon said circumferential circle.

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- 37. An apparatus according to claim 36, wherein during loading and unloading all of said receivers are disposed either over said carriers on said conveying device, or over central receiving points of said processing stations.
- 38. An apparatus according to claim 22, wherein a control device is provided for a simultaneous opening and closing of said receivers.